

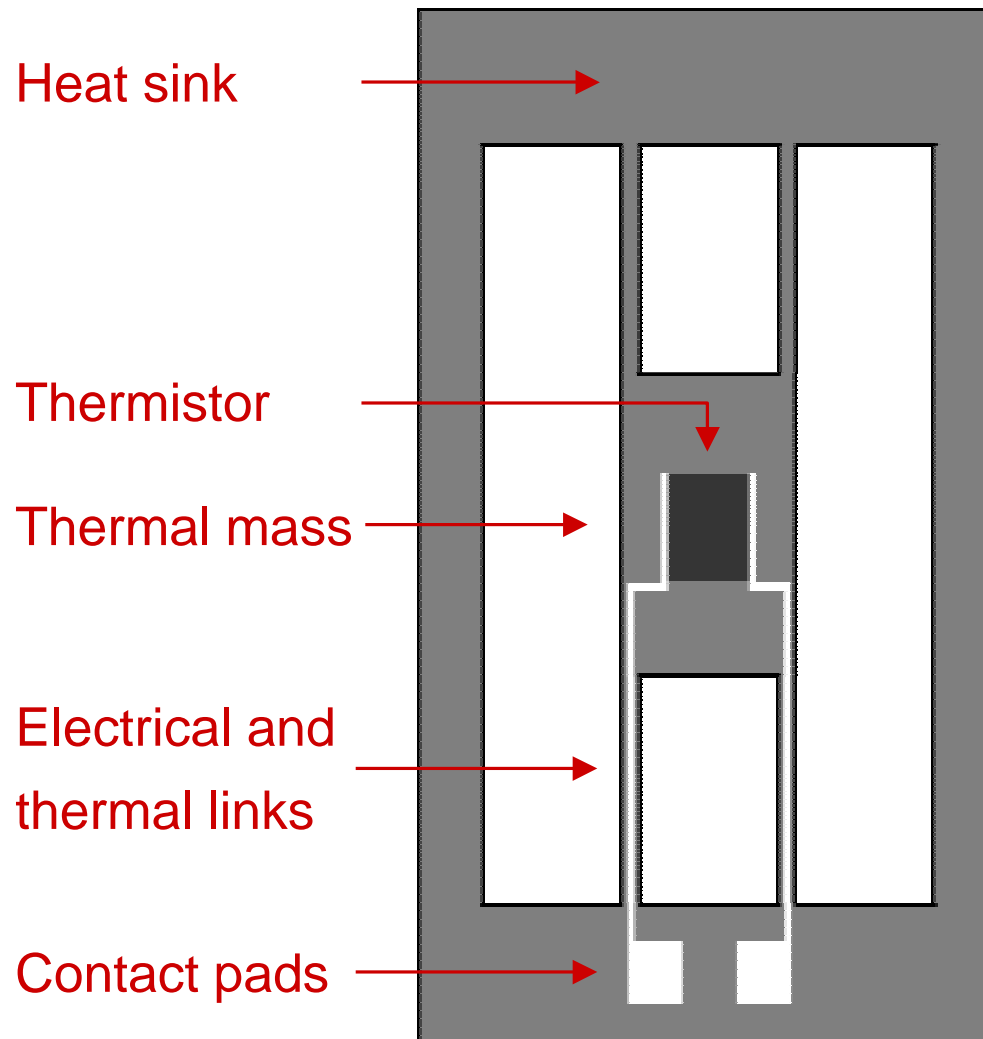


FABRICATION OF SILICON BOLOMETERS WITH BULK MICROMACHINING TECHNOLOGY

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- ❖ Implanted silicon thermistor (integrated circuit technology)
- ❖ Suspended thermal mass and integrated links (bulk micromachining technology)

